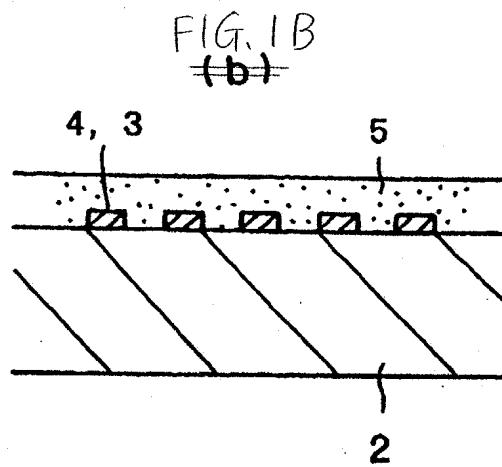
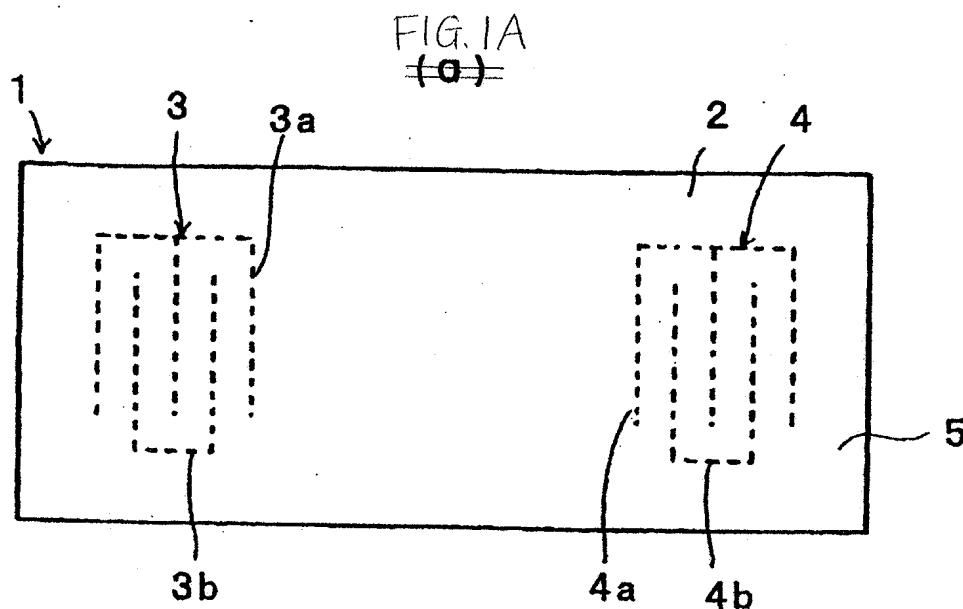


【書類名】

【図面】

【図1】



ELECTROMECHANICAL COUPLING COEFFICIENTS FOR A RAYLEIGH

WAVE,  $K^2$  WHEN A ZnO THIN FILM WITH EULERIAN ANGLES ( $0^\circ, 0^\circ, 0^\circ$ )

IS FORMED ON A QUARTZ SUBSTRATE WITH EULERIAN ANGLES ( $0^\circ, 119.75^\circ, 35^\circ$ )

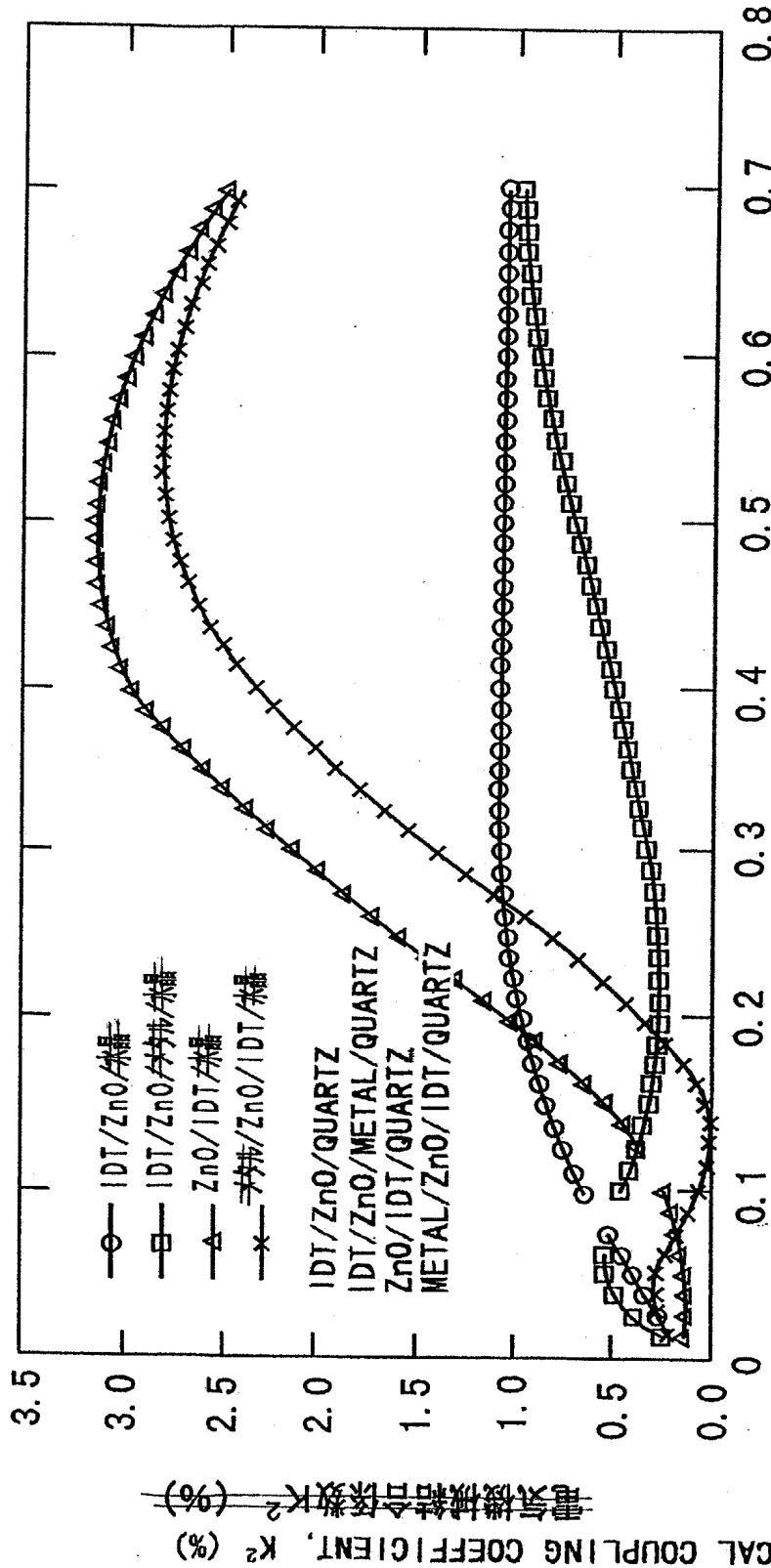
オイラー角 ( $0^\circ, 119.75^\circ, 35^\circ$ ) の基板上にオイラー角 ( $0^\circ, 0^\circ, 0^\circ$ ) のZnO薄膜を

形成したときのセイリ=波の電気機械結合係数  $K^2$

整理番号 = D P 0 0 0 0 8 9

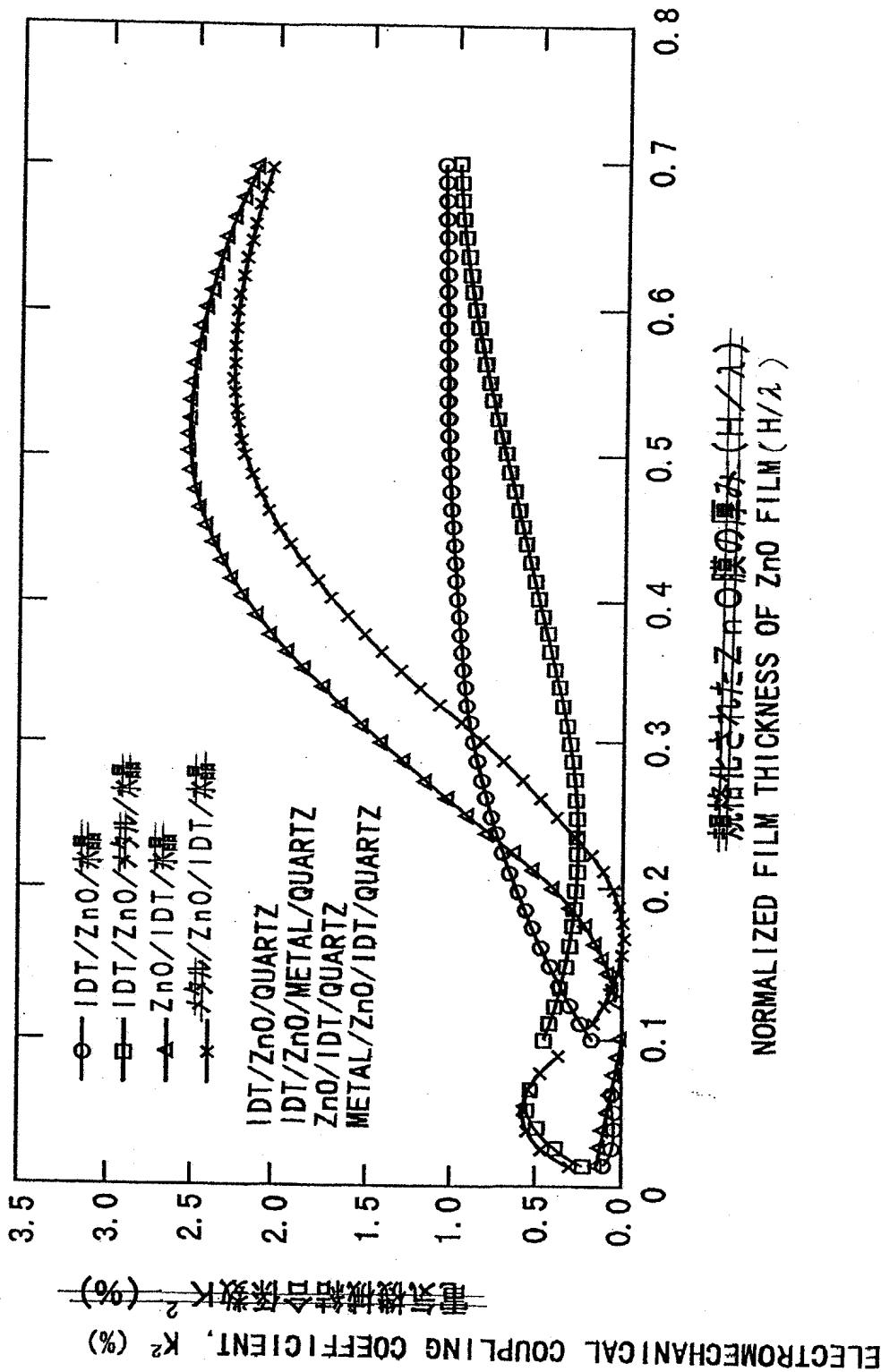
提出日 平成 12 年 4 月 28 日  
特願2000-130168 頁: 2 / 26

図2 FIG.2



規格化されたZnO膜の厚さ ( $H/\lambda$ )  
NORMALIZED FILM THICKNESS OF ZnO FILM ( $H/\lambda$ )

ELECTROMECHANICAL COUPLING COEFFICIENTS FOR THE RAYLEIGH  
 WAVE,  $K^2$  WHEN A ZnO THIN FILM WITH EULERIAN ANGLES (0°, 180°, 0°)  
 IS FORMED ON A QUARTZ SUBSTRATE WITH EULERIAN ANGLES (0°, 119.75°, 35°)  
 オイラー角(0°、119.75°、35°)の水晶基板上にオイラー角(0°、180°、0°)のZnO薄膜を  
 形成したときの電気機械結合係数 $K^2$



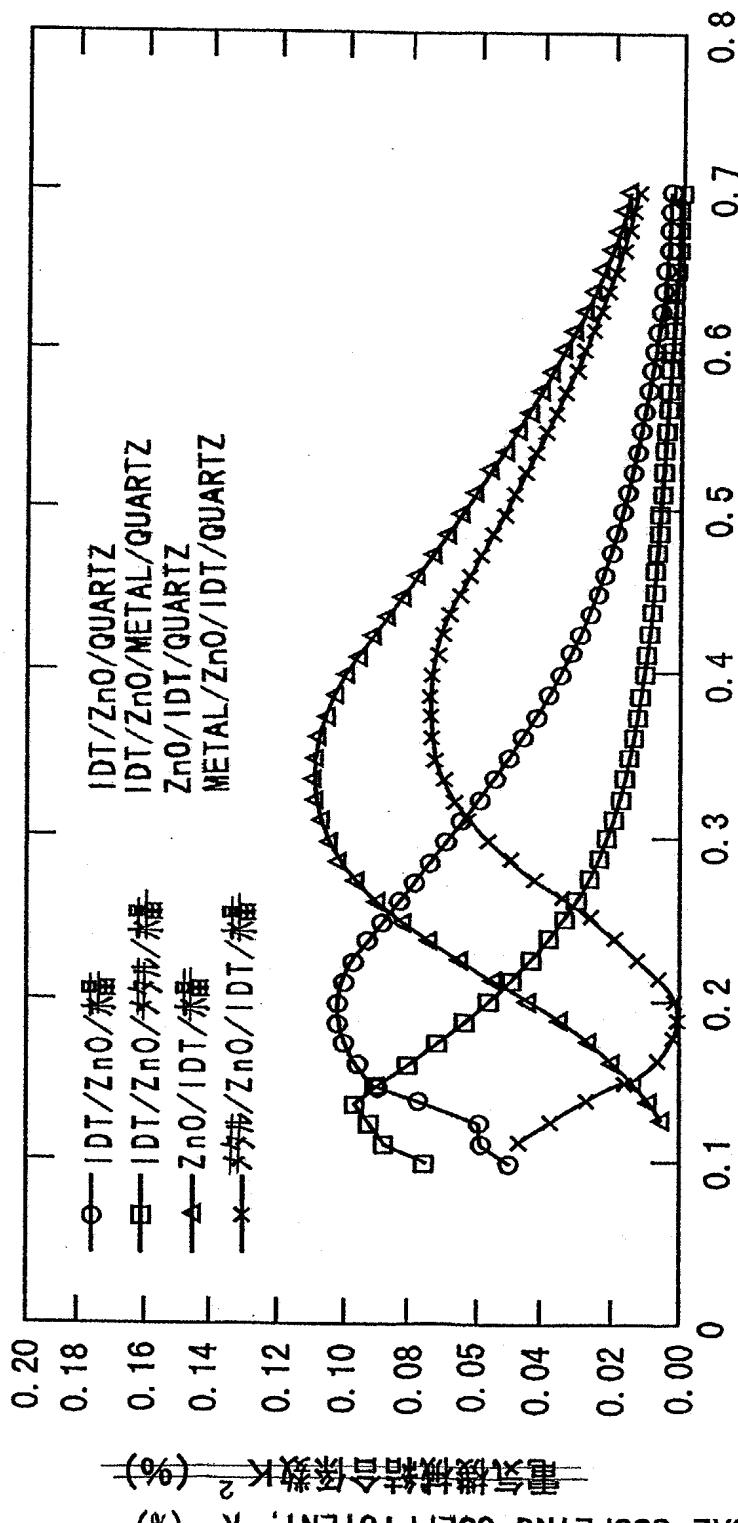
規格化されたZnO膜の厚み( $H/H_0$ )  
NORMALIZED FILM THICKNESS OF ZnO FILM ( $H/H_0$ )

ELECTROMECHANICAL COUPLING COEFFICIENTS FOR A SPURIOUS

WAVE,  $K_{sp}^2$  WHEN A ZnO THIN FILM WITH EULERIAN ANGLES (0°, 0°, 0°)

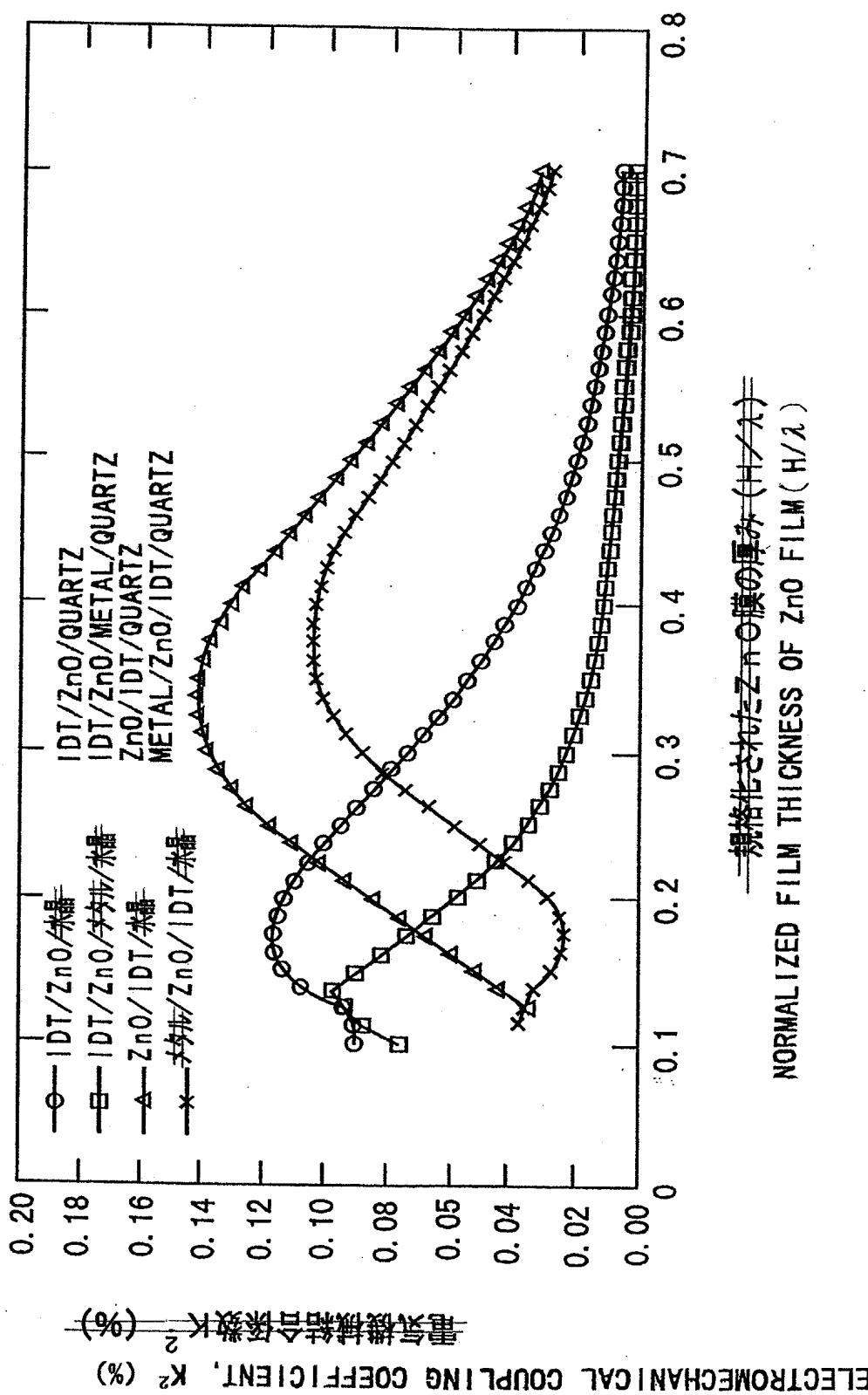
IS FORMED ON A QUARTZ SUBSTRATE WITH EULERIAN ANGLES (0°, 119.75°, 35°)

オイラー角(0°、+119.75°、35°)の水晶基板上にオイラー角(0°、0°、0°)のZnO薄膜を  
形成したときのレインフロー波の電気機械結合係数 $K^2$

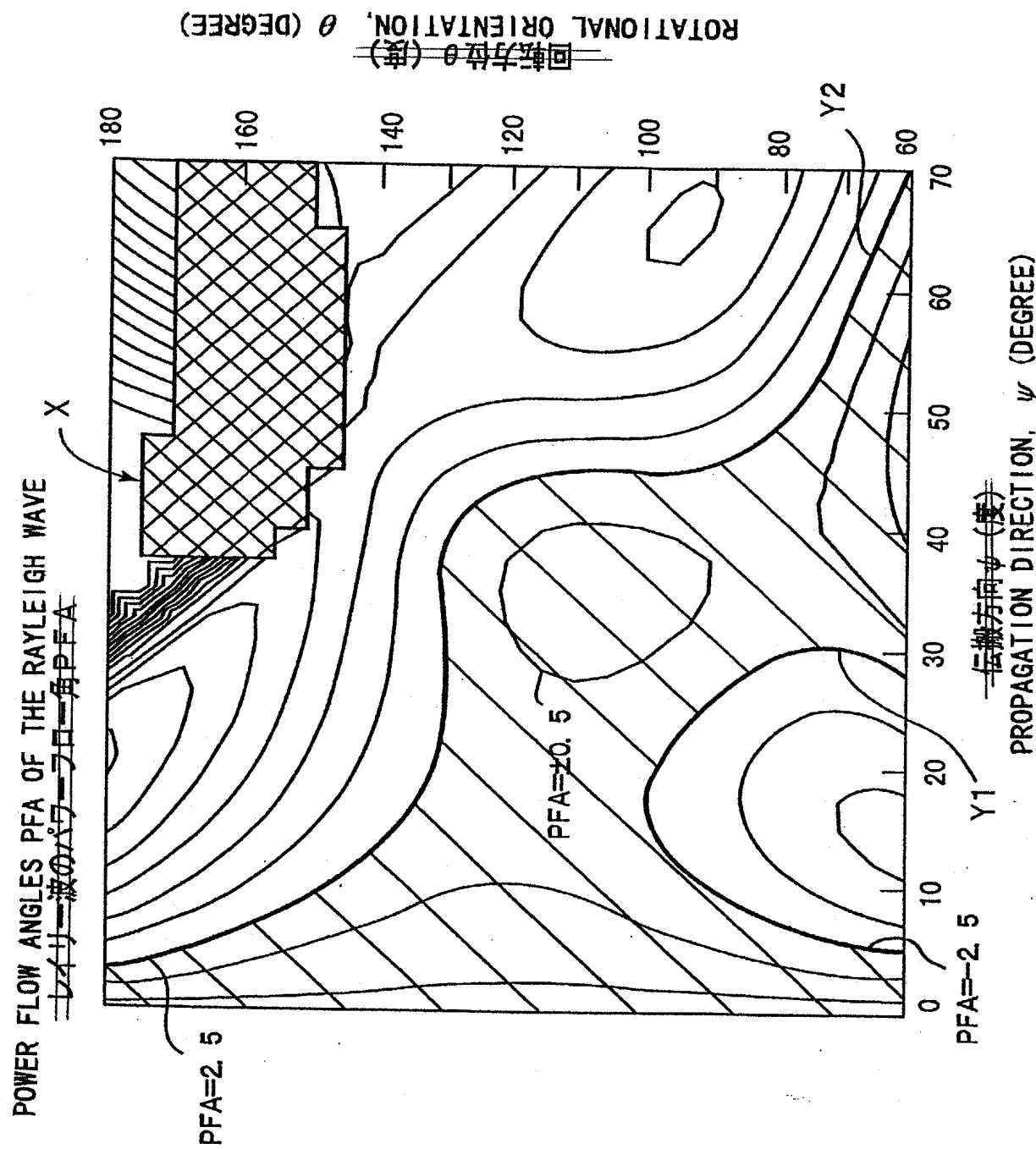


規格化されたZnO膜の厚み( $H/\lambda$ )  
NORMALIZED FILM THICKNESS OF ZnO FILM ( $H/\lambda$ )

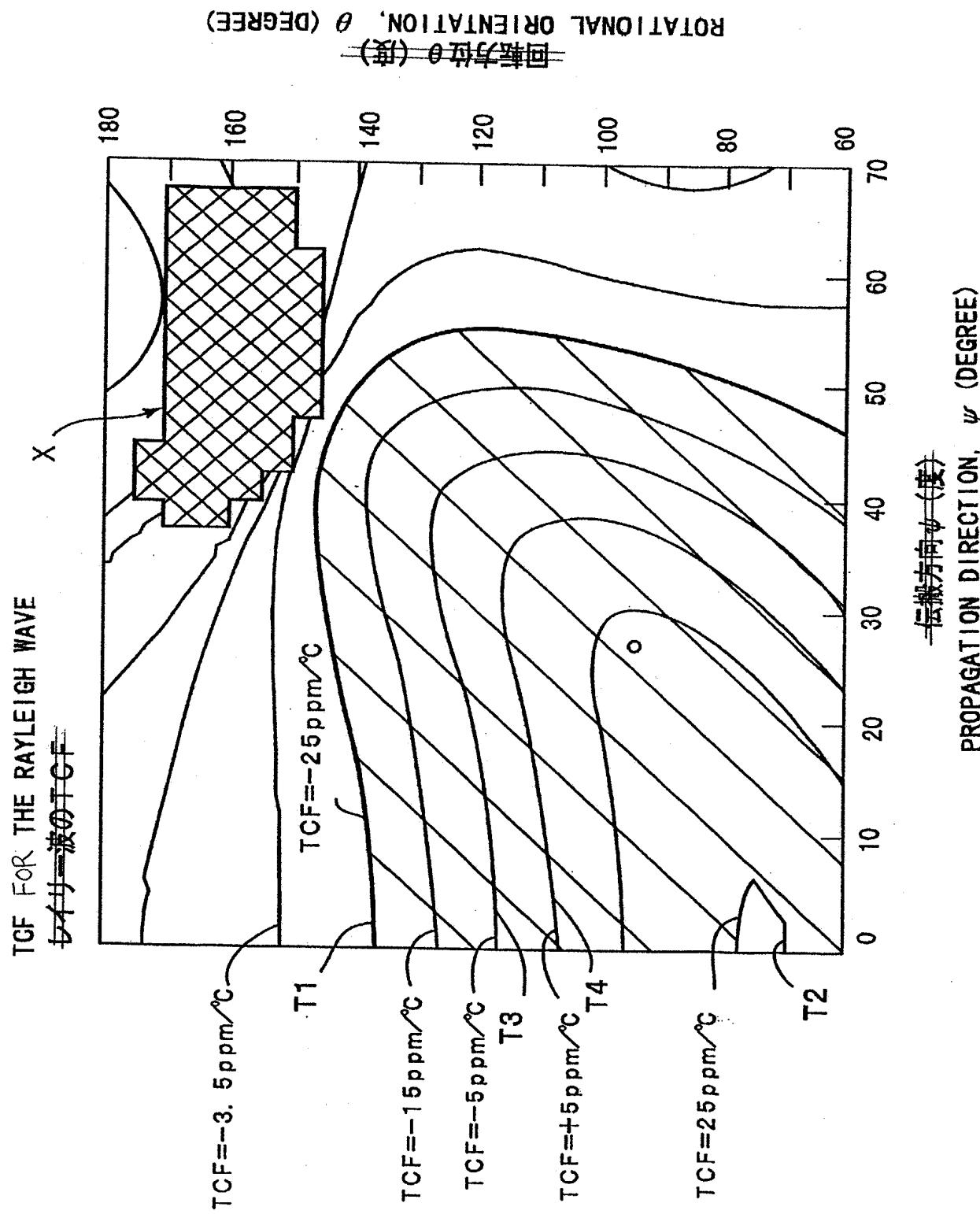
ELECTROMECHANICAL COUPLING COEFFICIENTS FOR THE SPURIOUS  
 WAVE,  $K_{sp}^2$ , WHEN A ZnO THIN FILM WITH EULERIAN ANGLES (0°, 180°, 0°)  
 IS FORMED ON A QUARTZ SUBSTRATE WITH EULERIAN ANGLES (0°, 119.75°, 35°)  
 オイラー角(0°、119.75°、35°)の水晶基板上にオイラー角(0°、180°、0°)のZnO薄膜を  
 形成したときのシザーワークの電気機械結合係数 $K^2$



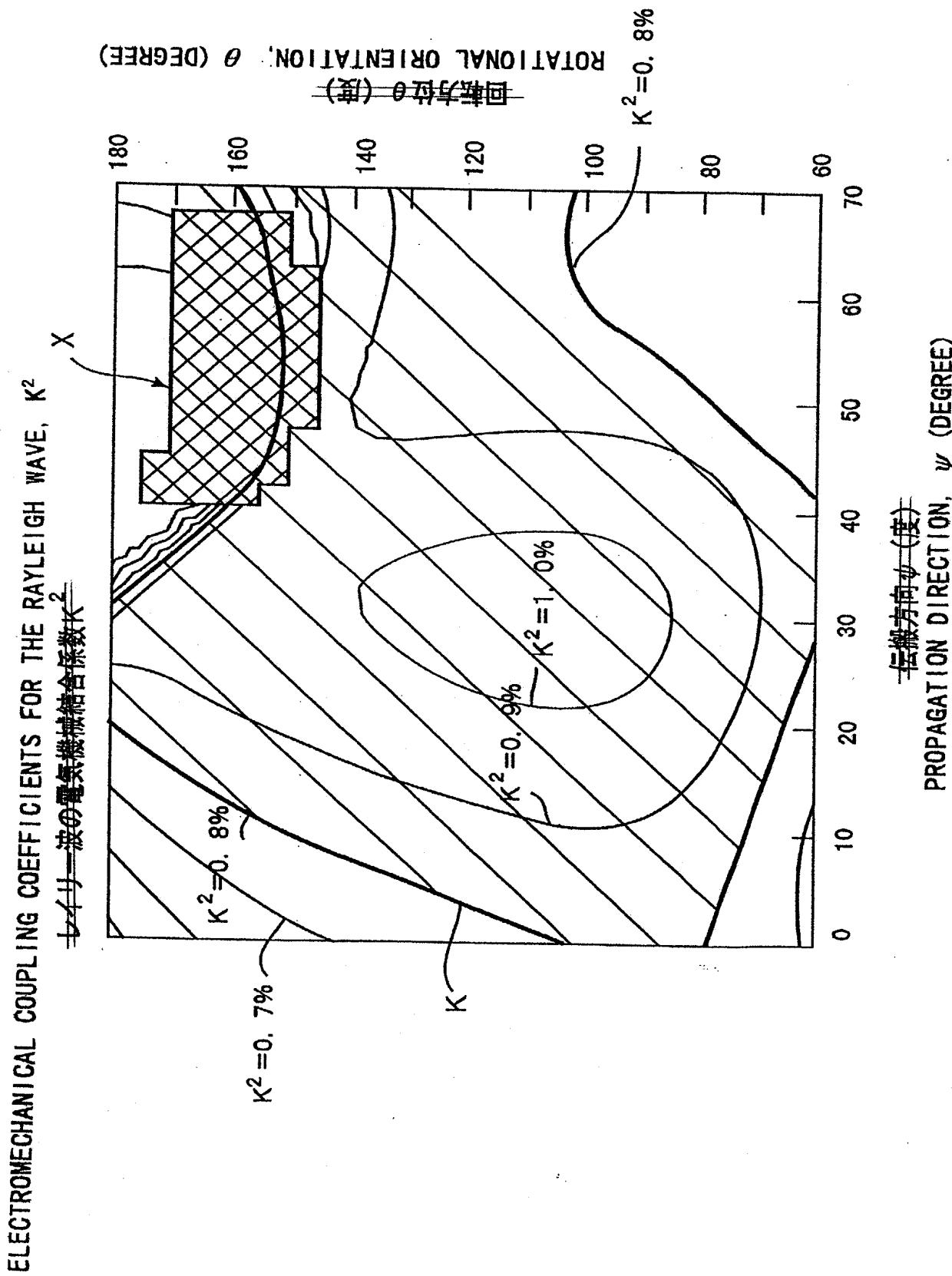
[図6] FIG. 6



【図7】 FIG.7

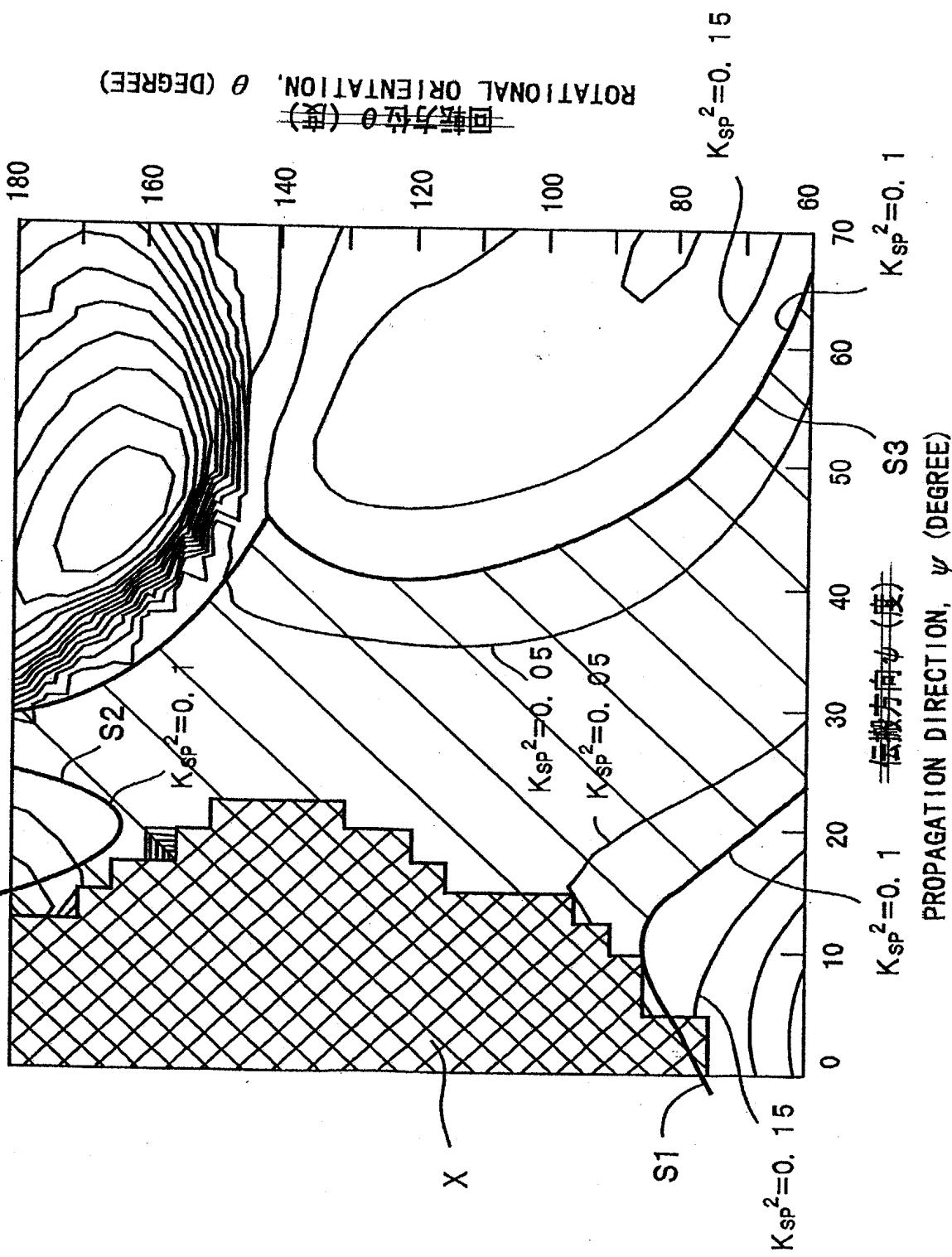


【図8】 FIG.8

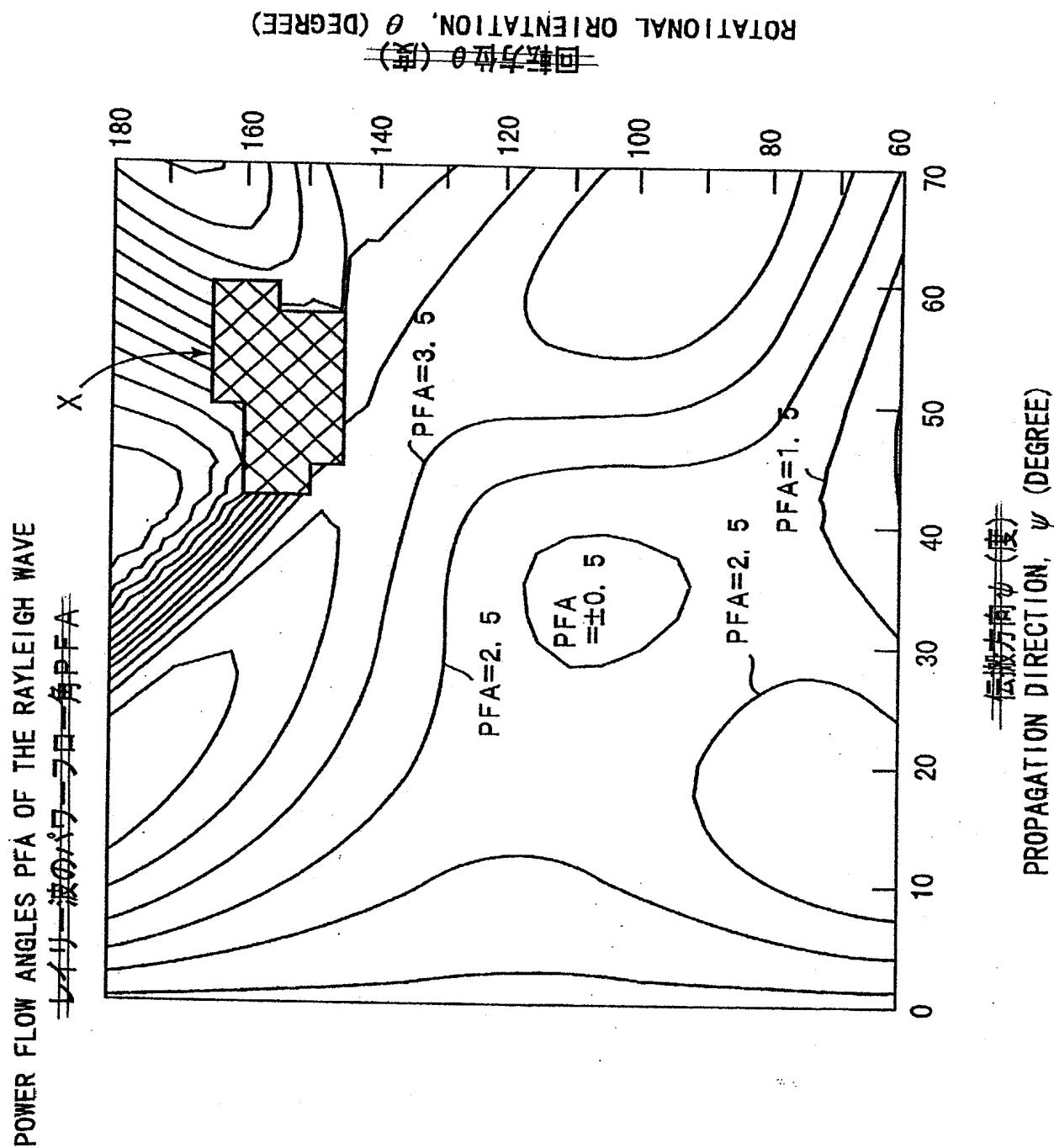


【図9】 FIG.9

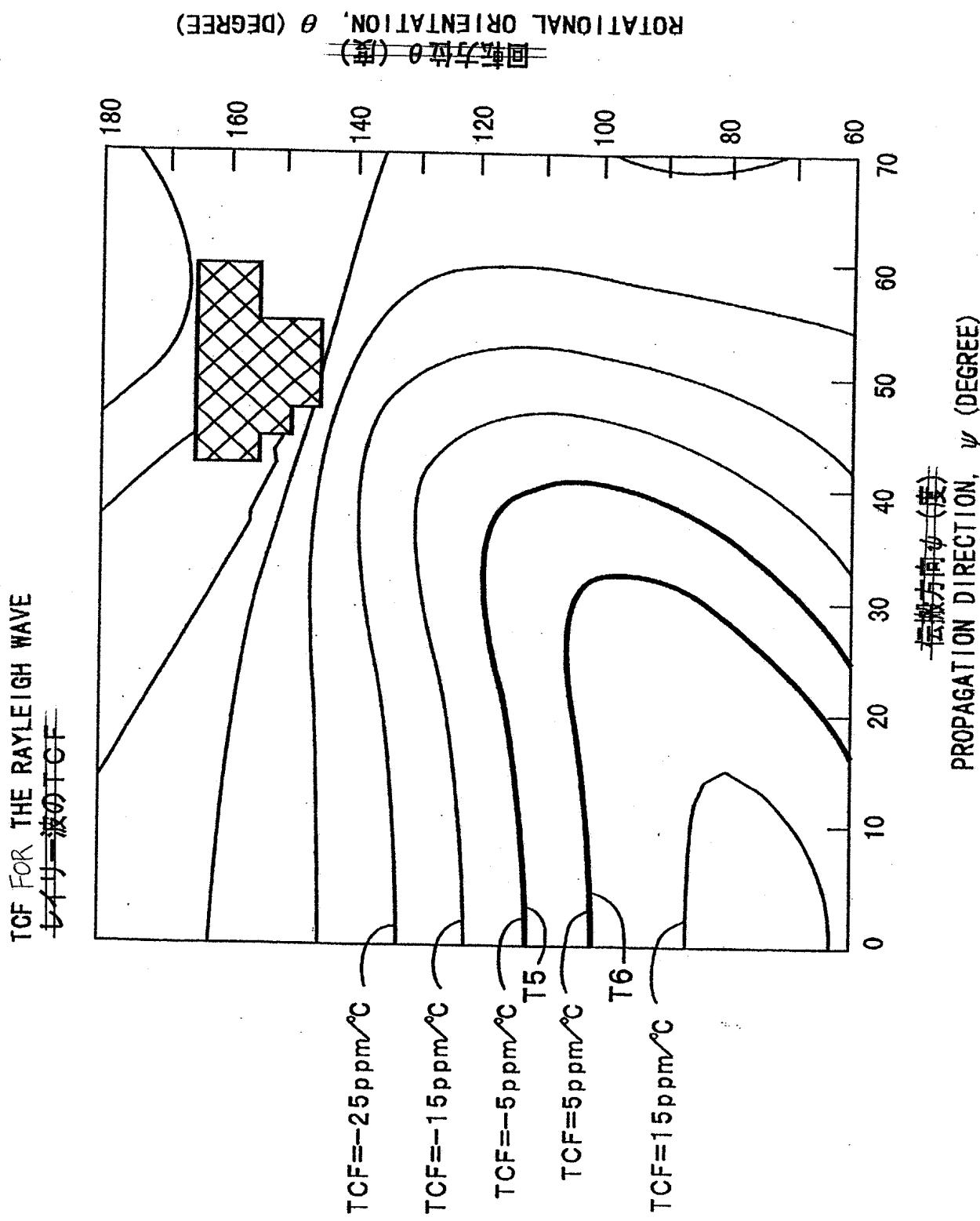
ELECTROMECHANICAL COUPLING COEFFICIENTS FOR THE SPURIOUS WAVE,  $K_{sp}^2$  (%)  
 ディアス波の電気機械結合係数  $K_{sp}^2$  (%)



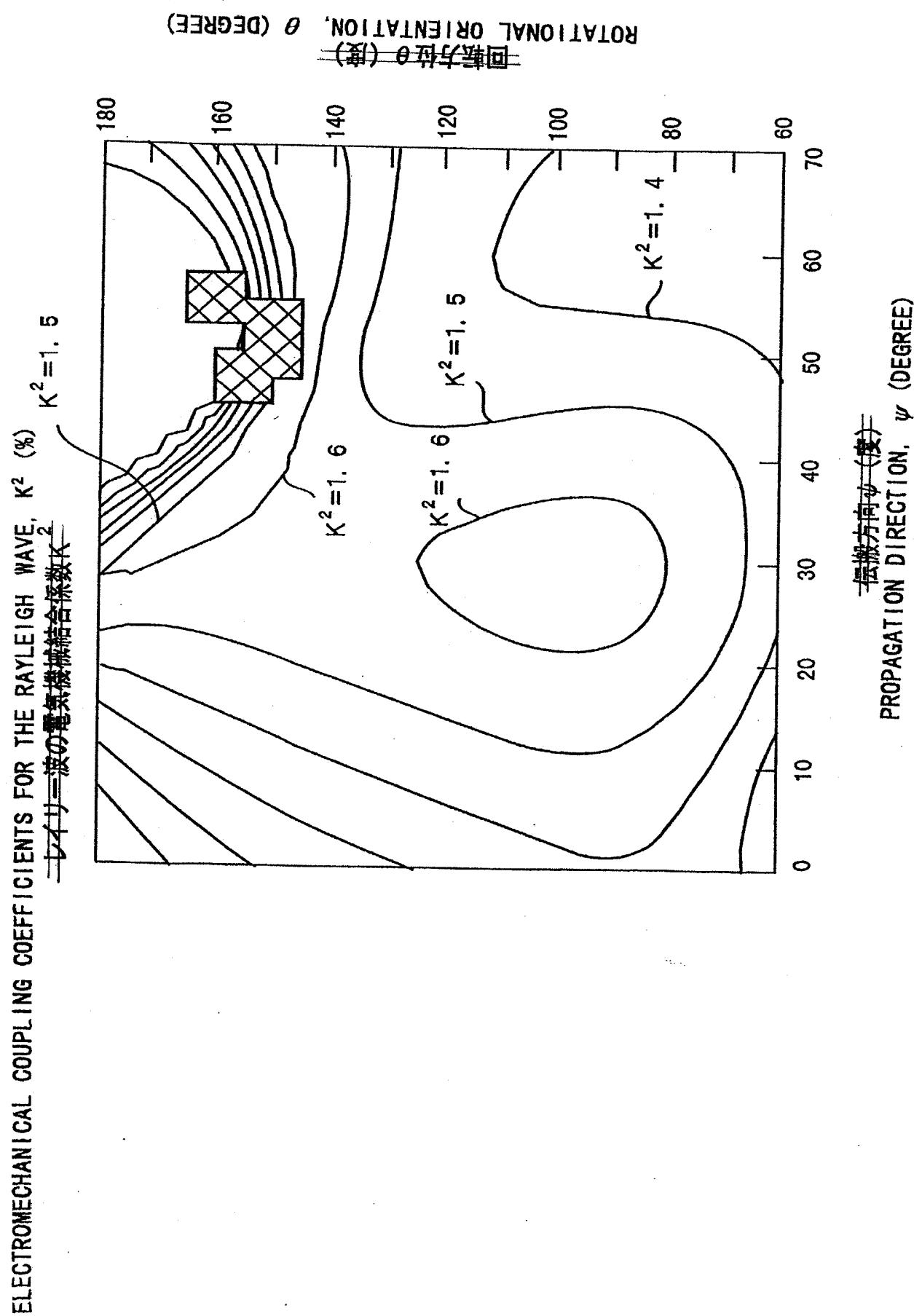
【図10】 FIG.10



[図11] FIG.11

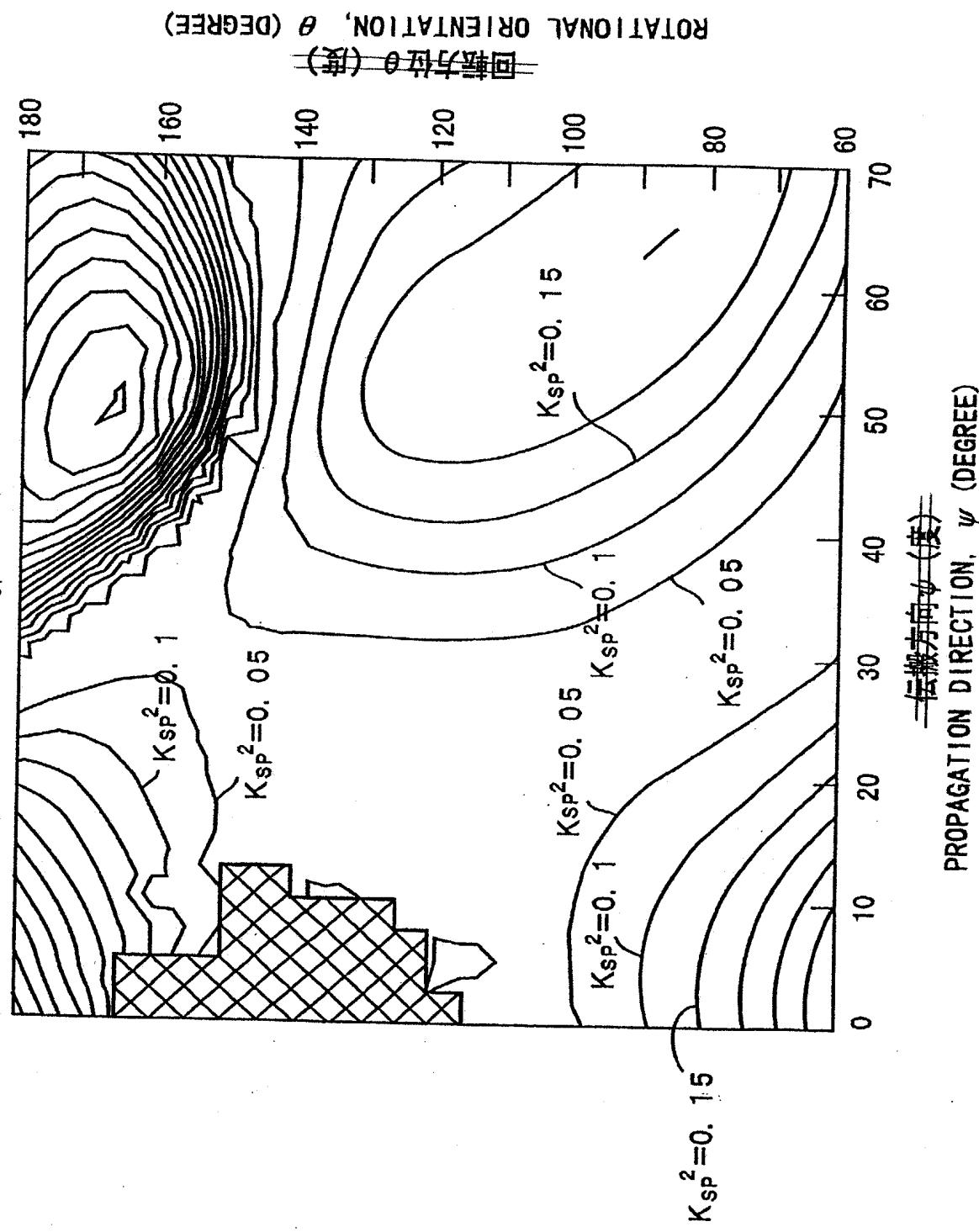


【図12】 FIG. 12



ELECTROMECHANICAL COUPLING COEFFICIENTS FOR THE SPURIOUS WAVE,  $K_{SP}^2$  (%)

アダマス接の電気機械結合係数( $K_{SP}^2$ %)

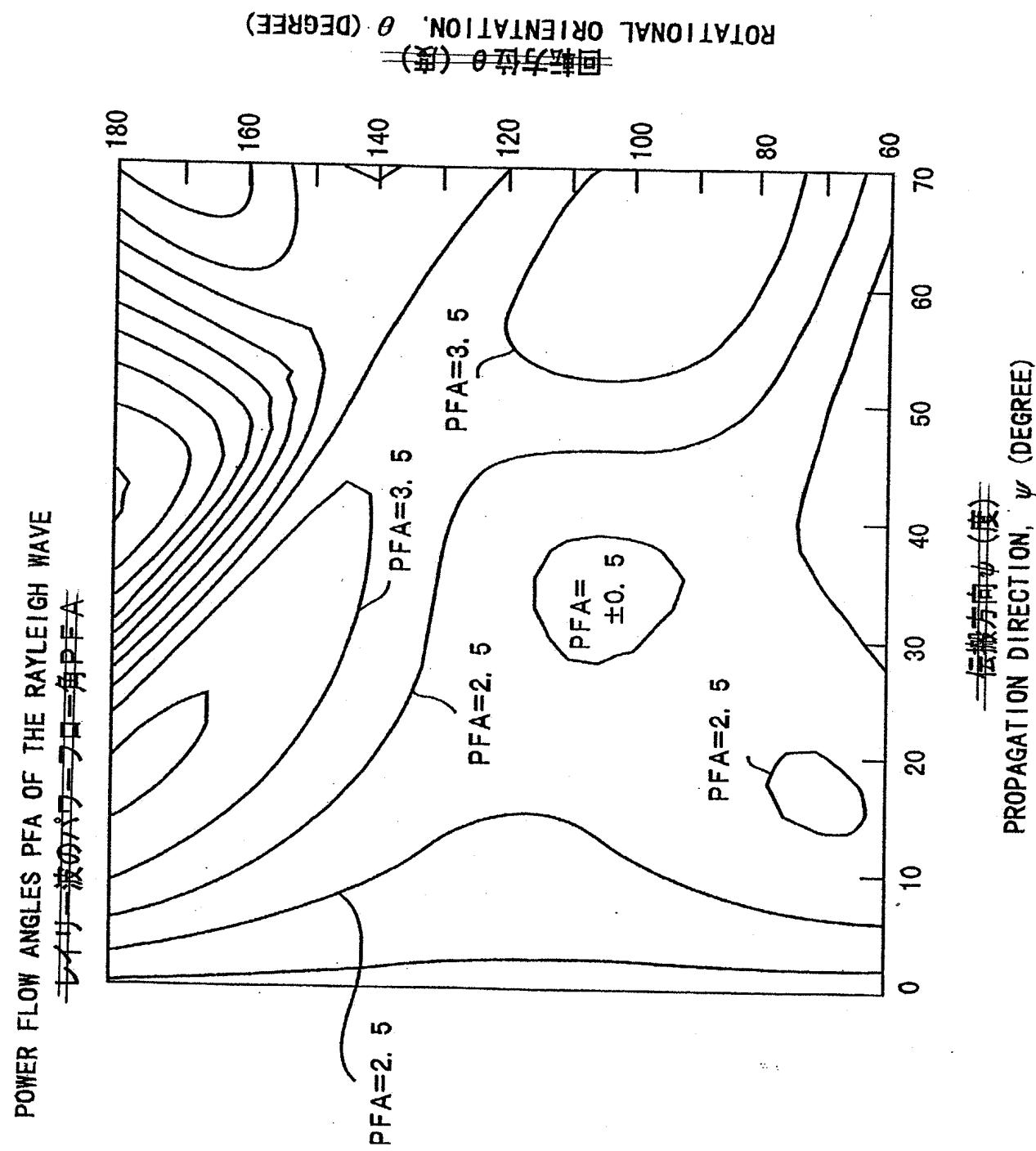


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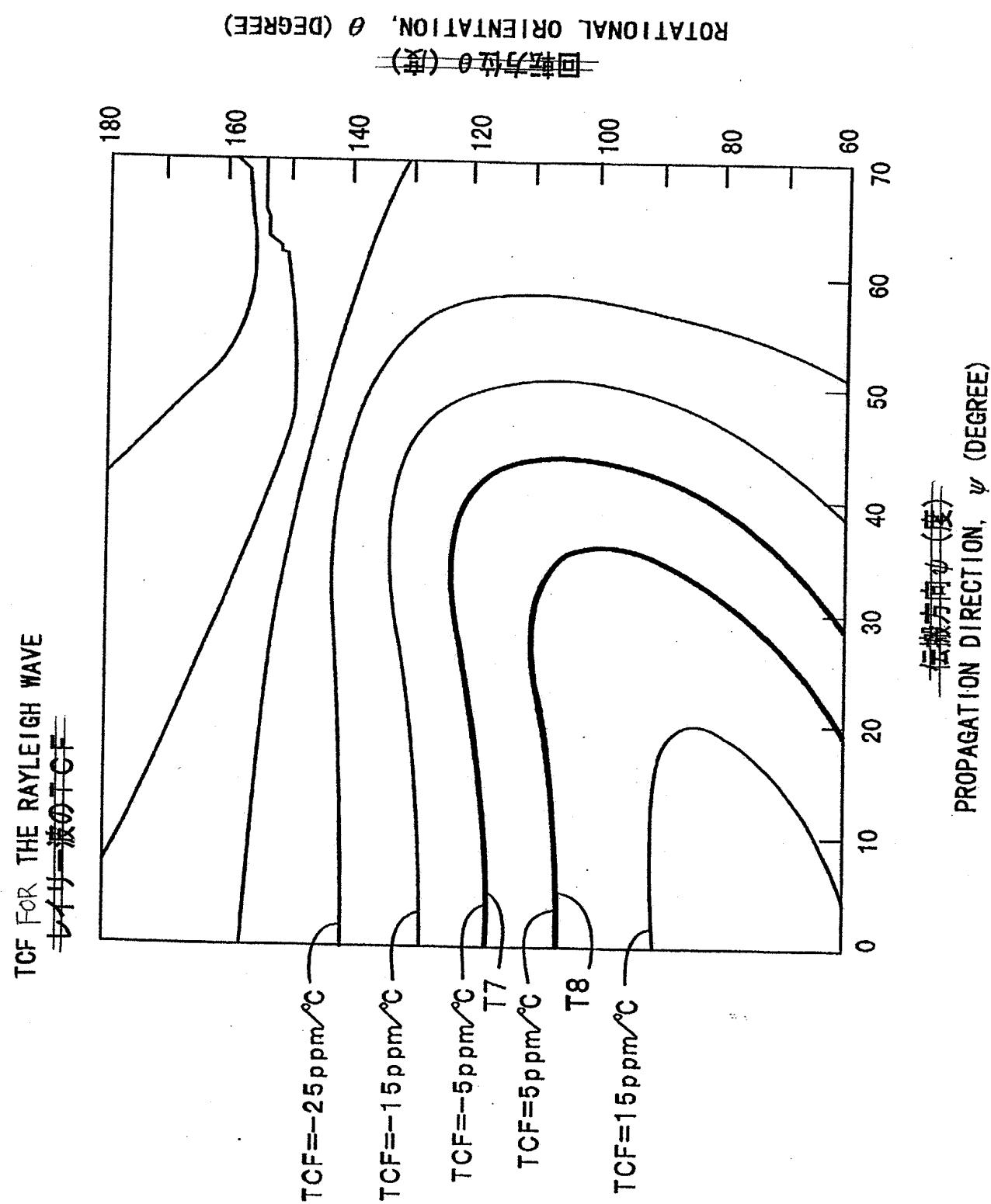
提出日 平成12年 4月28日  
特願2000-130168 頁: 13/ 26

【図13】 FIG.13

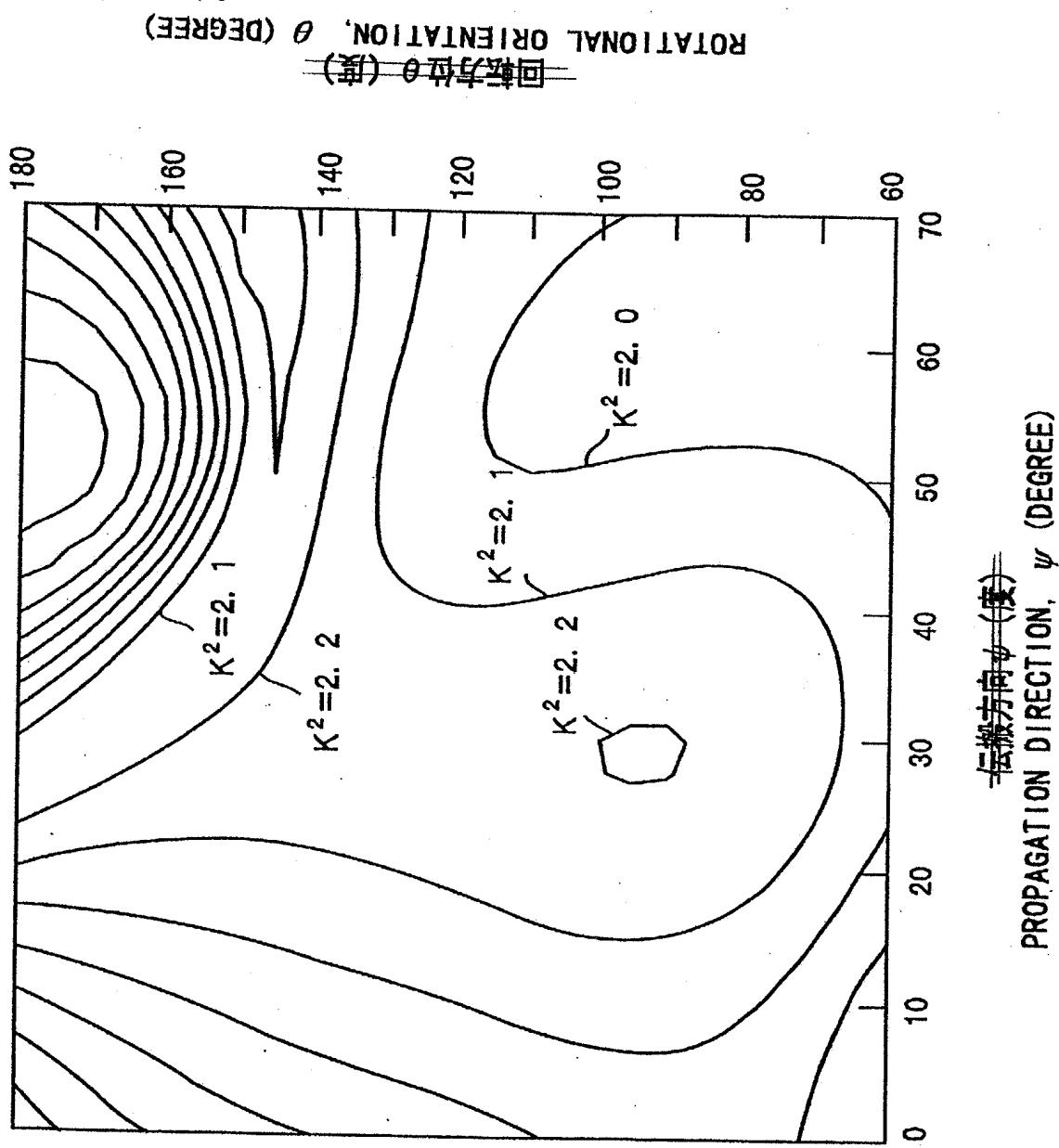
【図14】 FIG.14



【図15】 FIG.15



ELECTROMECHANICAL COUPLING COEFFICIENTS FOR THE RAYLEIGH WAVE,  $K^2$  (%)  
 ベルト＝波分電気機械結合係数  $K^2$  (%)



整理番号=DP000089

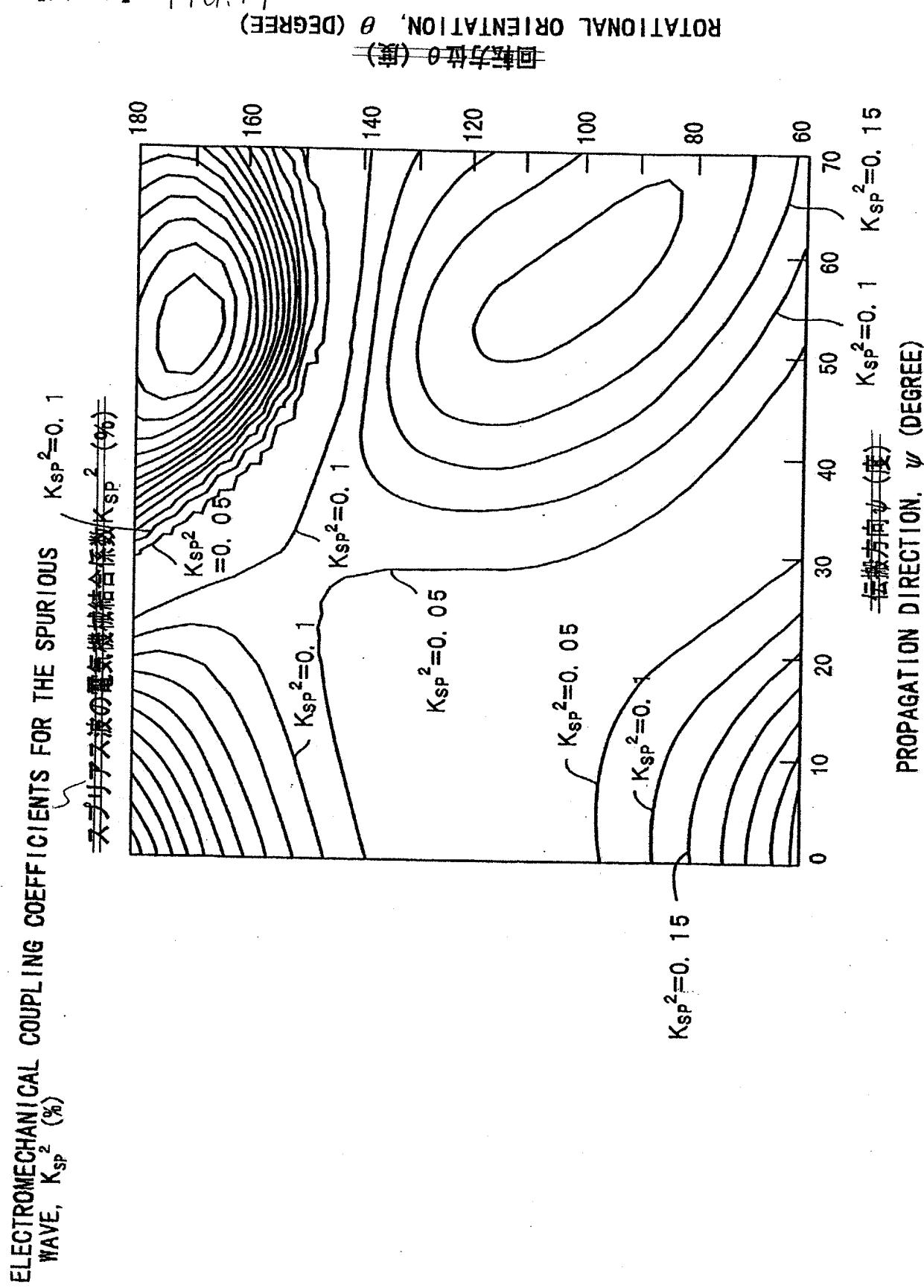
提出日 平成12年 4月28日  
 特願2000-130168 頁: 16/ 26

【図16】 FIG. 16

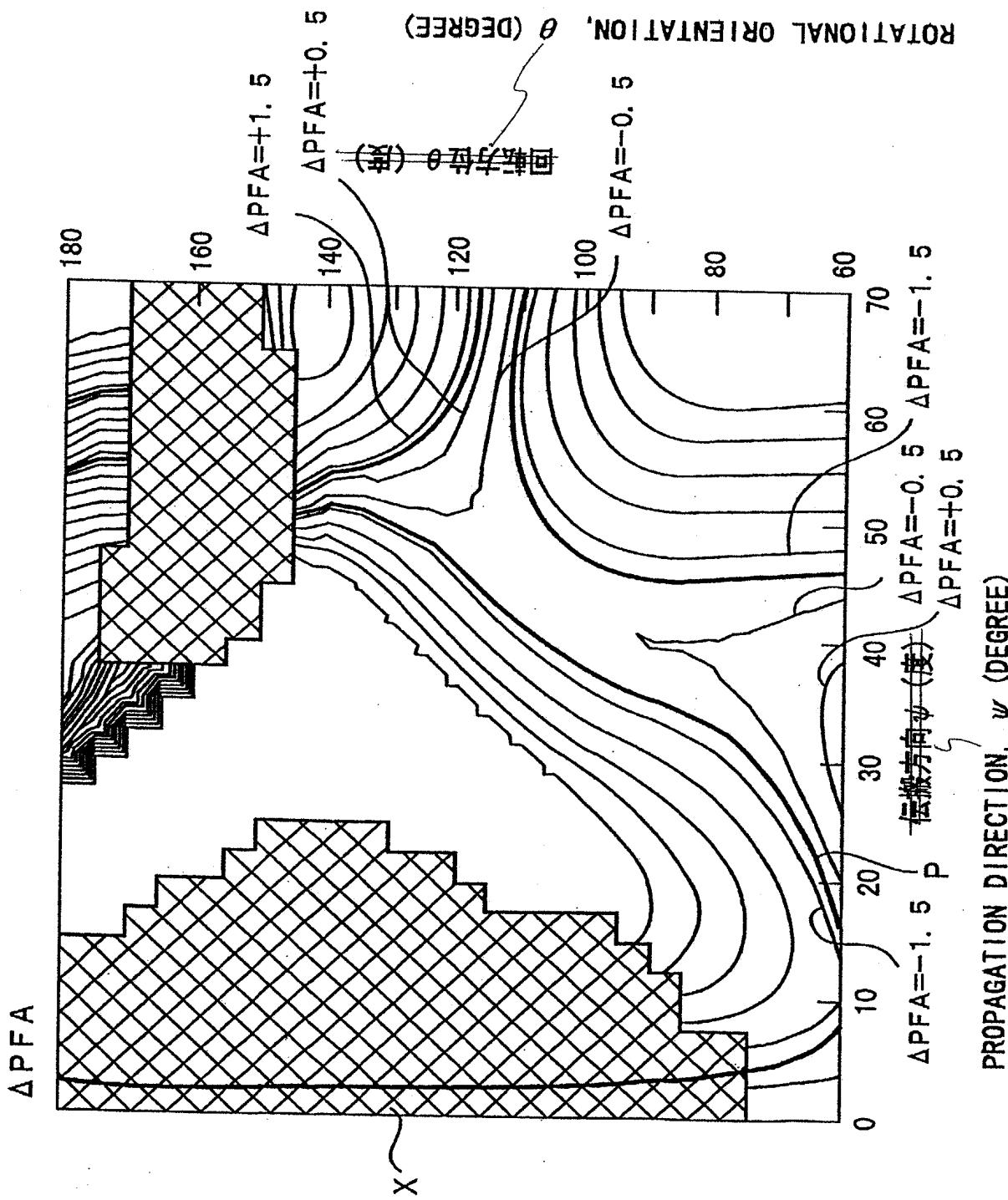
ROTATIONAL ORIENTATION,  $\theta$  (DEGREE)  
 回転方位θ(度)

PROPAGATION DIRECTION,  $\psi$  (DEGREE)  
 伝搬方向ψ(度)

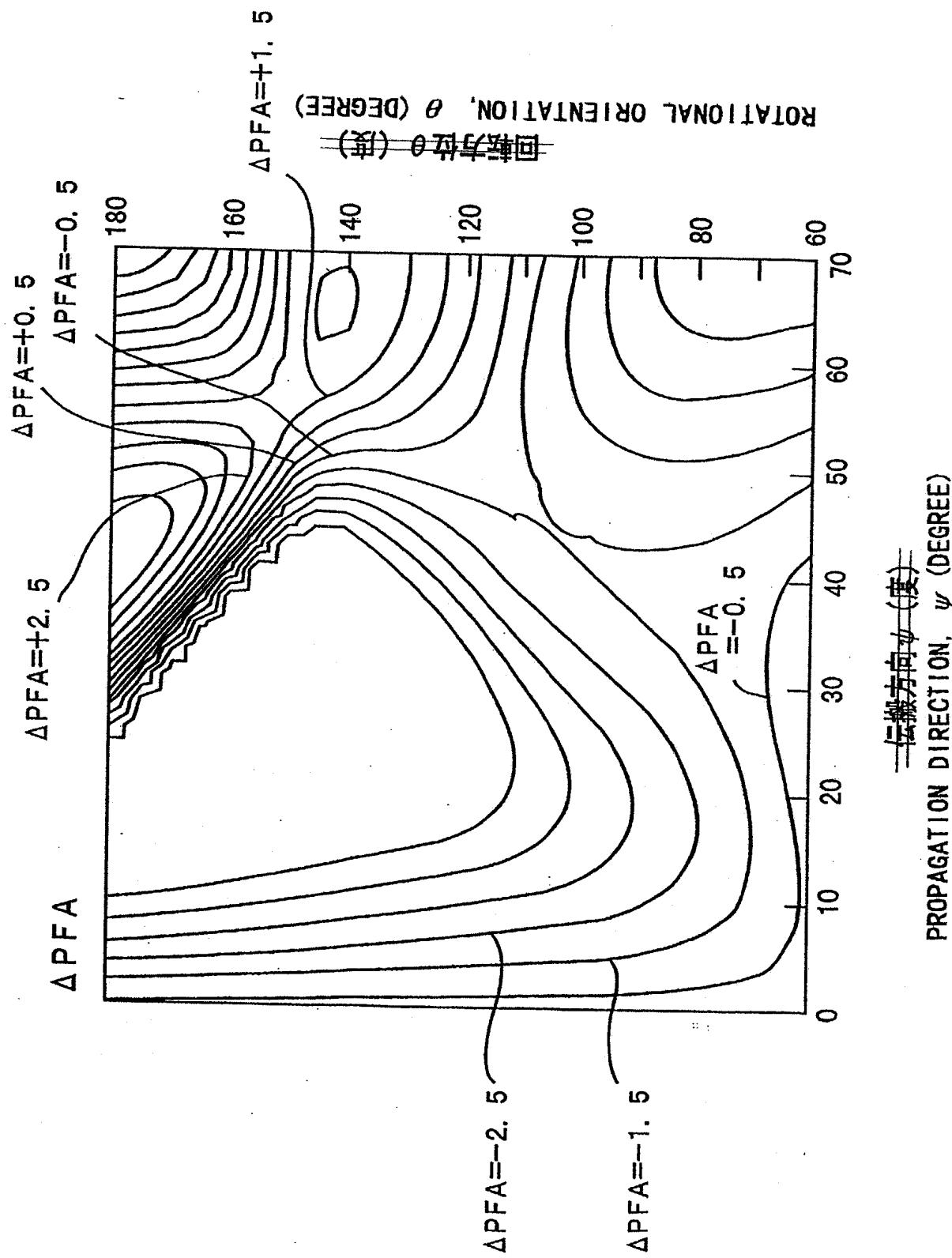
【図17】 FIG.17



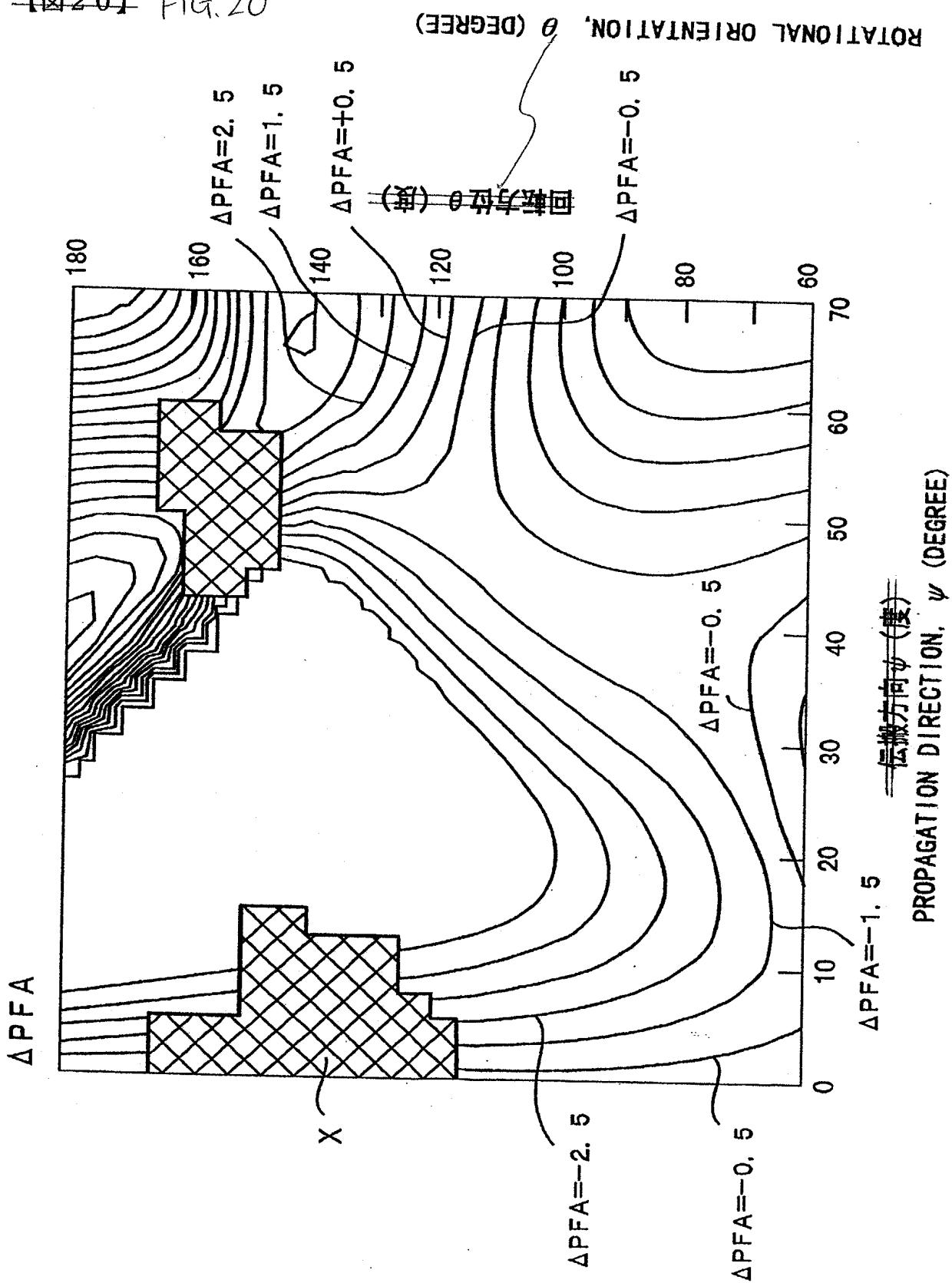
【図18】 FIG.18



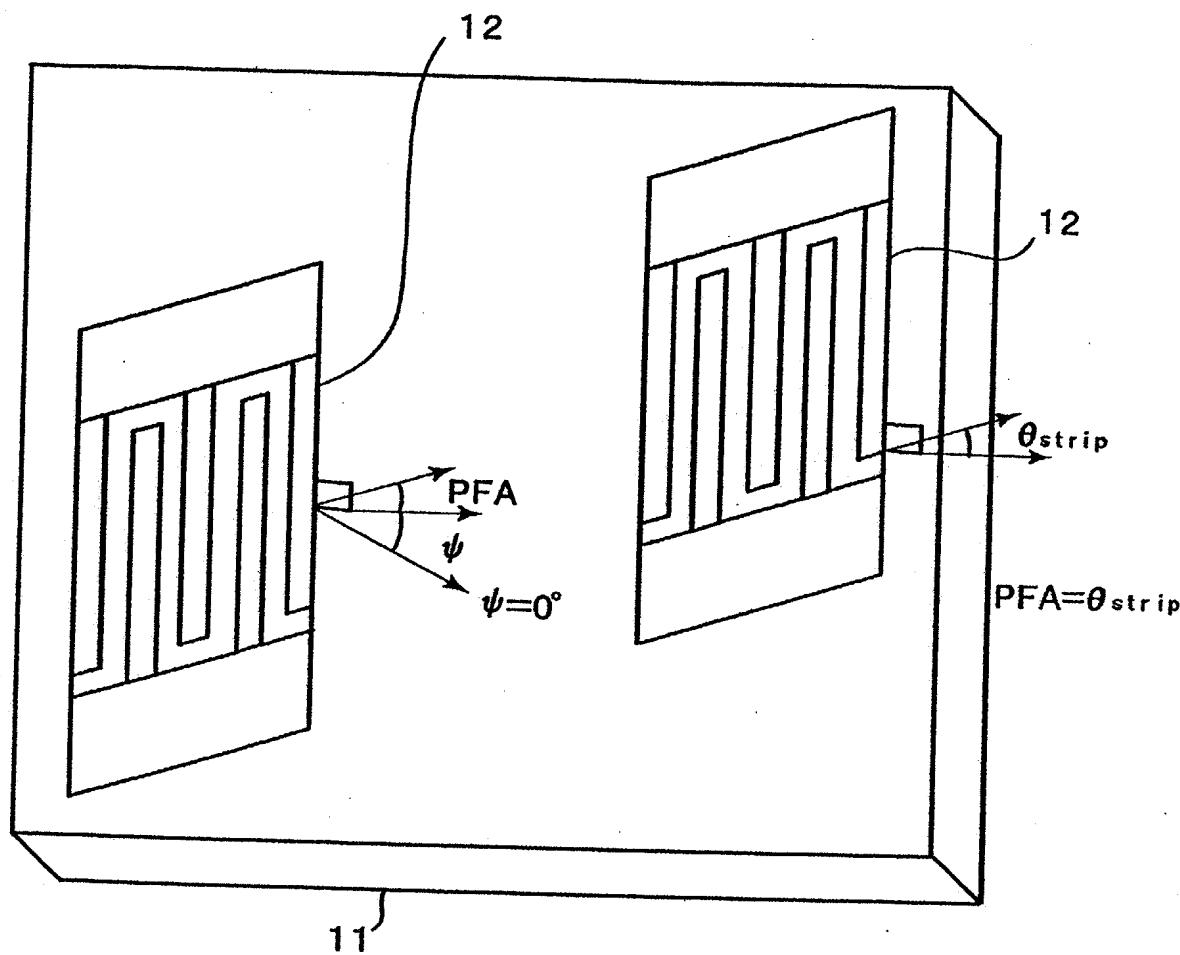
[図19] FIG.19



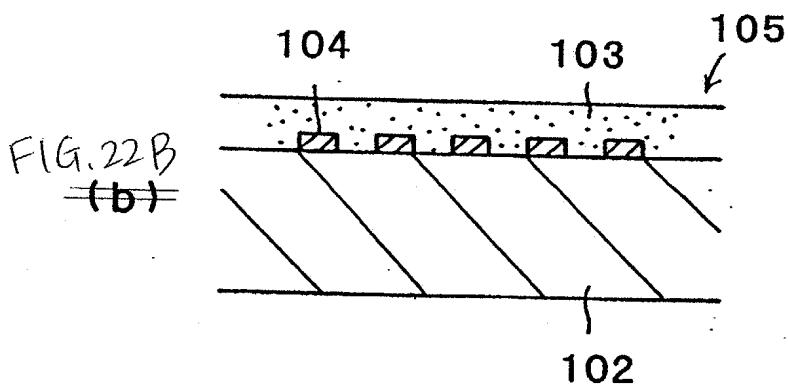
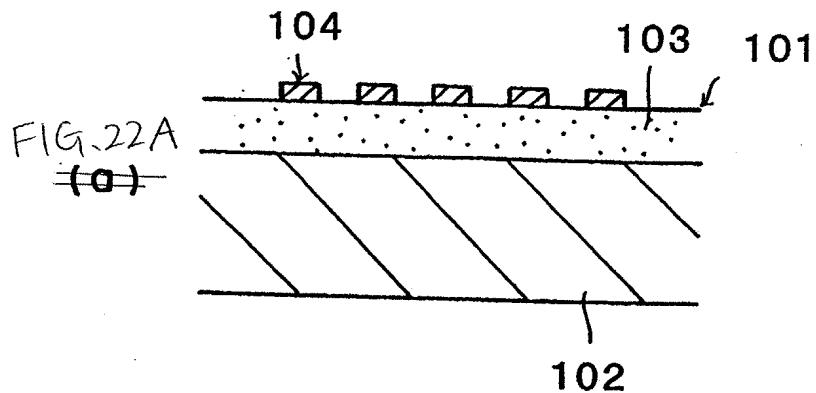
【図20】 FIG.20



【図2-1】 FIG.21



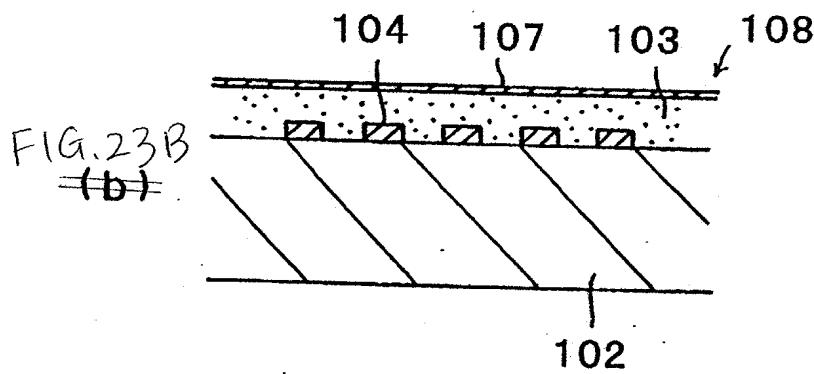
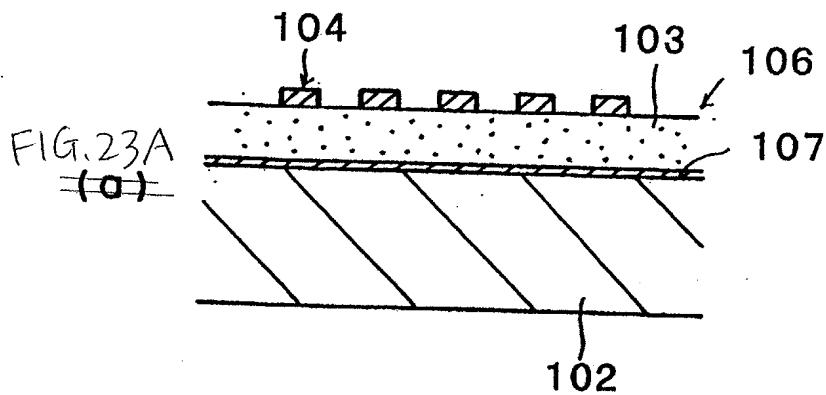
[図22]



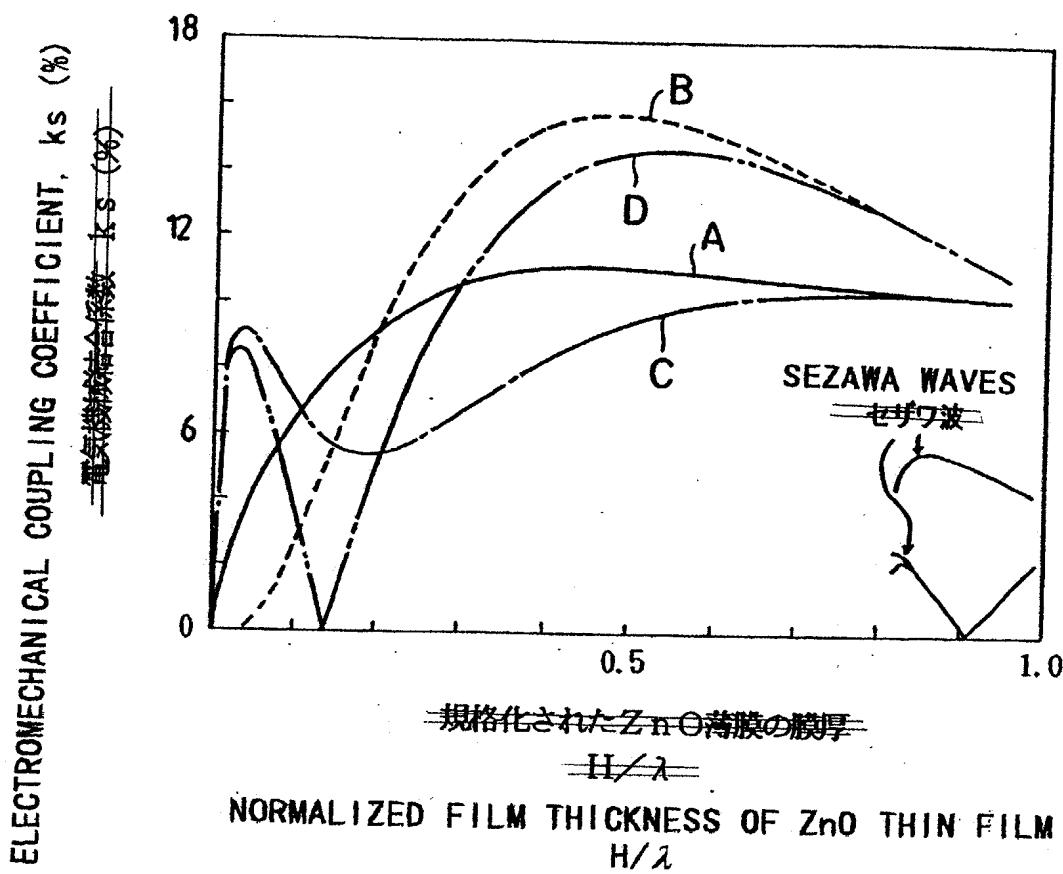
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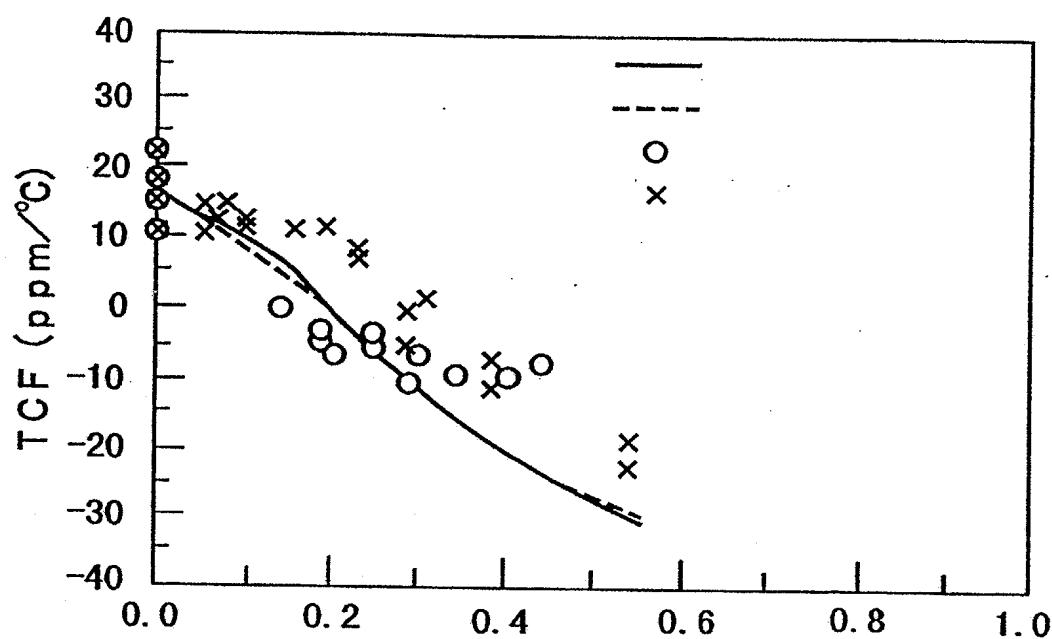
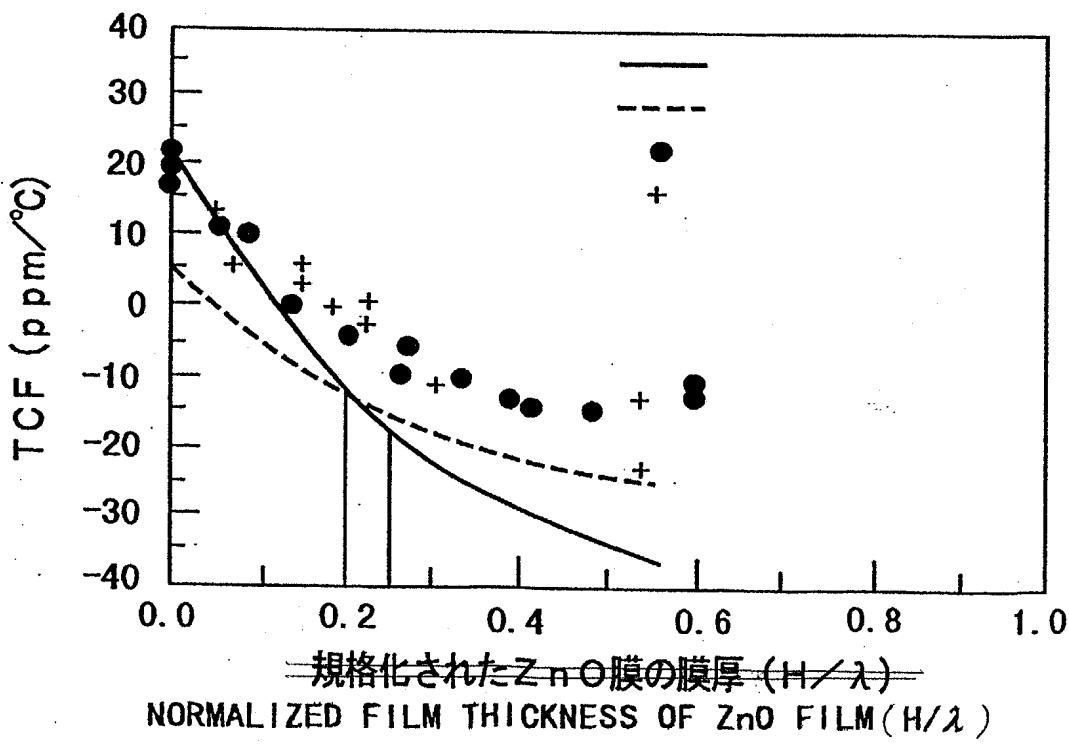
【図23】



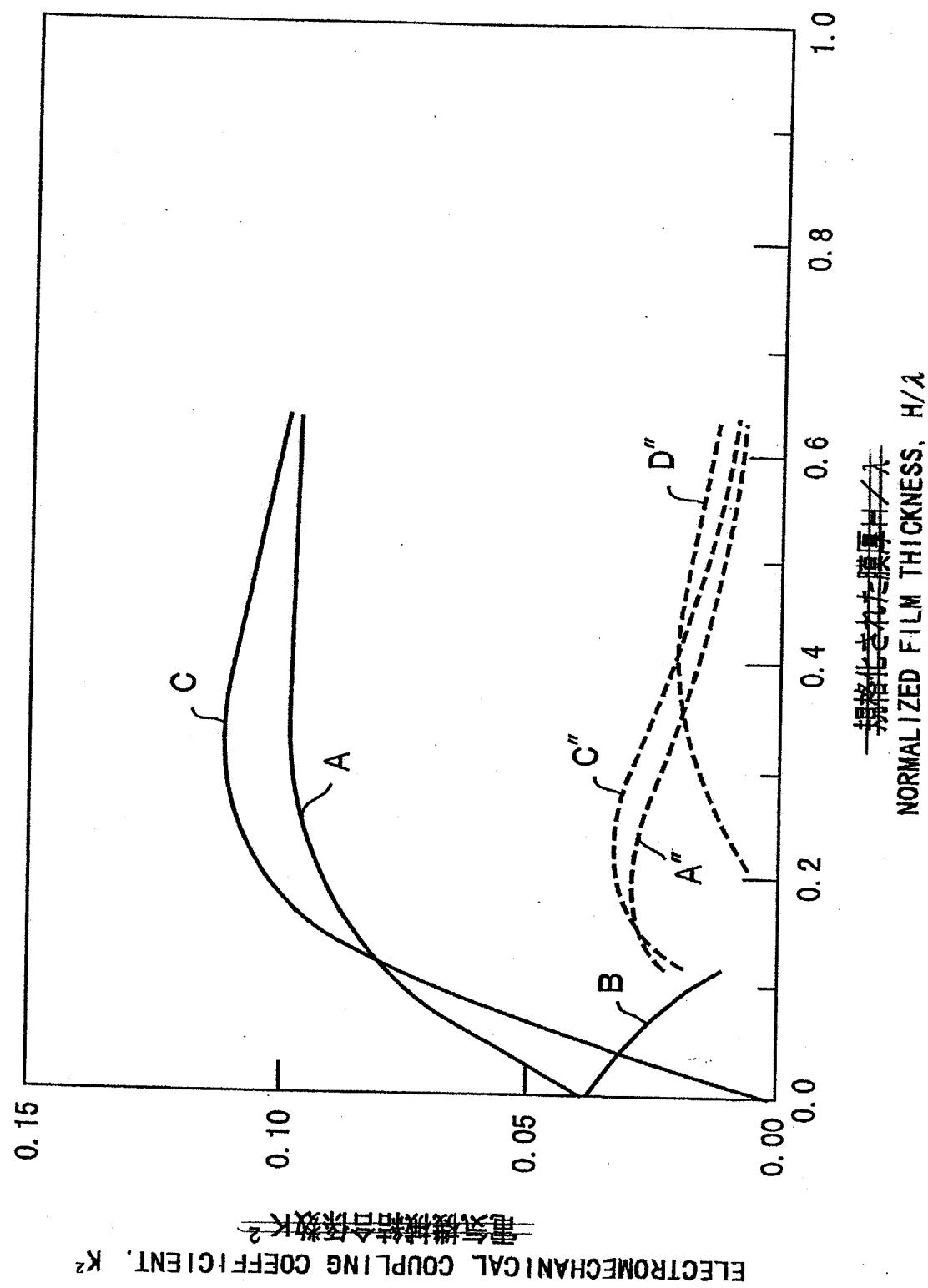
【図24】 FIG.24



[図25]

FIG.25A  
(a)規格化されたZnO膜の膜厚 ( $H/\lambda$ )  
NORMALIZED FILM THICKNESS OF ZnO FILM ( $H/\lambda$ )FIG.25B  
(b)規格化されたZnO膜の膜厚 ( $H/\lambda$ )  
NORMALIZED FILM THICKNESS OF ZnO FILM ( $H/\lambda$ )

【図2-6】 FIG.26



2001-04-23

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FROM MURATA MFG.

TO

KEATING & BENNETT

P.05/05

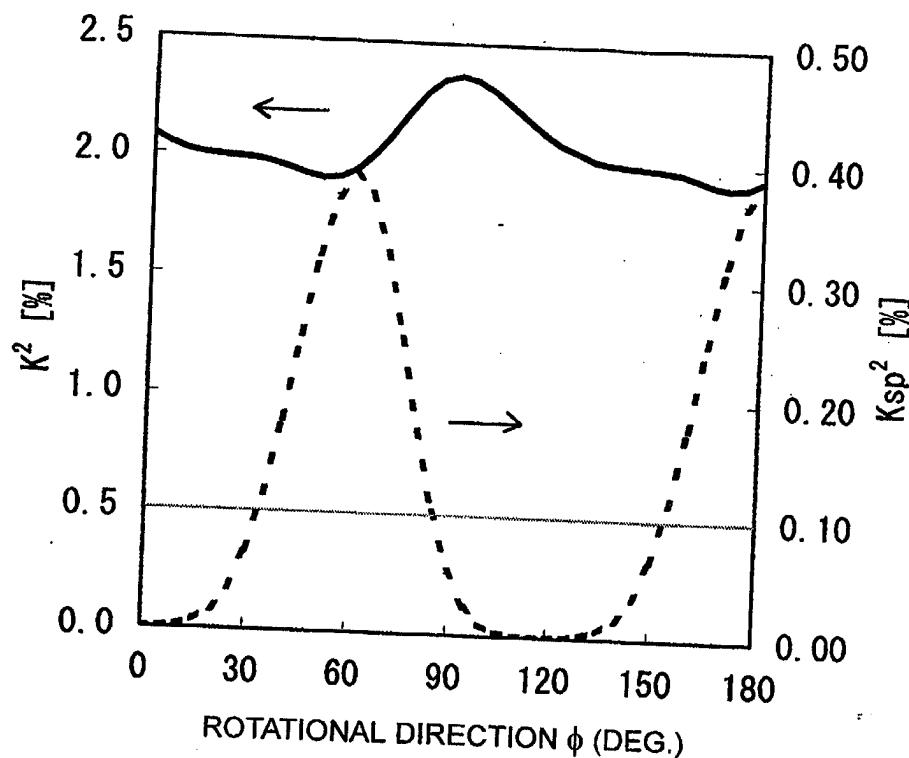


FIG. 27